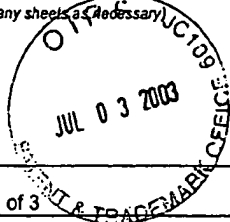


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Filing Date	January 18, 2000
First Named Inventor	Ahn, Kie
Group Art Unit	2823
Examiner Name	Berezny, Neal

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Attorney Docket No: 303.648US1

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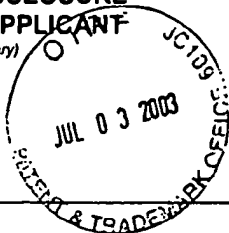
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Application Number	09/484303
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Group Art Unit	2823
Examiner Name	Berezny, Neal

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Examiner Name	Berezny, Neal

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Attorney Docket No: 303.648US1

Examiner Initials*	Cite No <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
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